

FORM PTO-1449 O I P E INFORMATION DISCLOSURE STATEMENT APR 25 2008 PATENT & TRADEMARK OFFICE				ATTY. DOCKET 033082 M 343	SERIAL NO. 10/591,476	
				APPLICANT: Yasuhiko KOJIMA		
				FILING DATE September 1, 2006	GROUP ART UNIT 1751	

U.S. PATENT DOCUMENTS

*Examiner's Initials		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB-CLASS	FILING DATE, IF APPROPRIATE
	AA	3,198,167	August 3, 1965	R. Bakish et al.			
	AB	4,321,073	March 23, 1982	Blair			
	AC						
	AD						
	AE						
	AF						
	AG						

FOREIGN PATENT DOCUMENTS

*Examiner's Initials		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB-CLASS	TRANSLATION YES NO
	AH	2005/058789	6/30/2005	WO			
	AI						
	AJ						
	AK						
	AL						
	AM						
	AN						
	AO						
	AP						

OTHER INFORMATION (Including Author, Title, Date, Pertinent Pages, Etc.)

	AQ	Supplementary European Search Report (Application No. EP 04 74 6795)
	AR	MOUCHE M-J et al., "Metal-organic chemical vapor deposition of copper....precursor", THIN SOLID FILMS, ELSEVIER-SEQUOIA S.A. LAUSANNE, CH, vol. 262, 1995, pages 1-6, XP002347082, ISSN: 0040-6090
	AS	

EXAMINER:	DATE CONSIDERED:
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.